

POLISHING APPARATUS AND DRESSING METHOD

ABSTRACT OF THE DISCLOSURE

5 An apparatus for polishing a surface of a substrate by slidingly engaging the surface with a polishing surface of an abrasive member has a dressing member for dressing the polishing surface of the fixed abrasive member. The dressing member has a dressing surface provided with projections having an angular portion of an obtuse angle of not less than (100°) .

This Sheet Has Been Replaced

